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## APPLICANTS

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Jung-Sik Choi, Seoul, KOREA, REPUBLIC OF;\*\* CONTINUING DATA \*\*\*\* *Verified*This application is a CIP of 10/278,992 10/24/2002  
which is a DIV of 09/686,624 10/12/2000 PAT 6,706,646  
*Verified*\*\* FOREIGN APPLICATIONS \*\*\*\* *Verified*REPUBLIC OF KOREA 2003-10159 02/18/2003  
REPUBLIC OF KOREA 2000-23448 05/02/2000

## IF REQUIRED, FOREIGN FILING LICENSE GRANTED

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Foreign Priority claimed 35 USC 119 (a-d) conditions met	<input checked="" type="checkbox"/> yes <input type="checkbox"/> no <input checked="" type="checkbox"/> yes <input type="checkbox"/> no <input type="checkbox"/> Met after Allowance	STATE OR COUNTRY KOREA, REPUBLIC OF	SHEETS DRAWING 8	TOTAL CLAIMS 25	INDEPENDENT CLAIMS 2
Verified and Acknowledged Examiner's Signature: <i>[Signature]</i>	Initials: <i>[Initials]</i>				

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## TITLE

Method of forming a silicon oxide layer in a semiconductor manufacturing process

All Fees